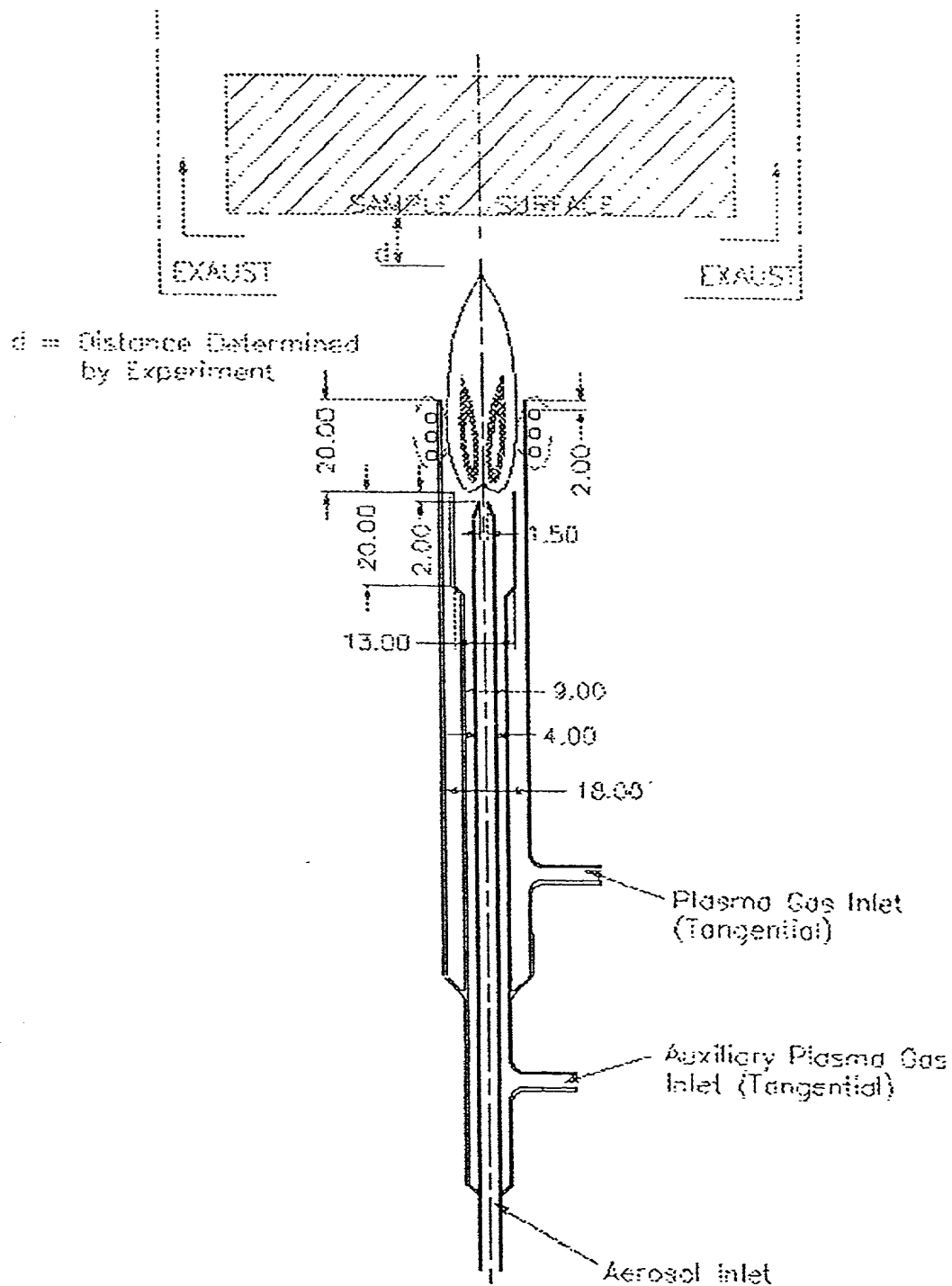
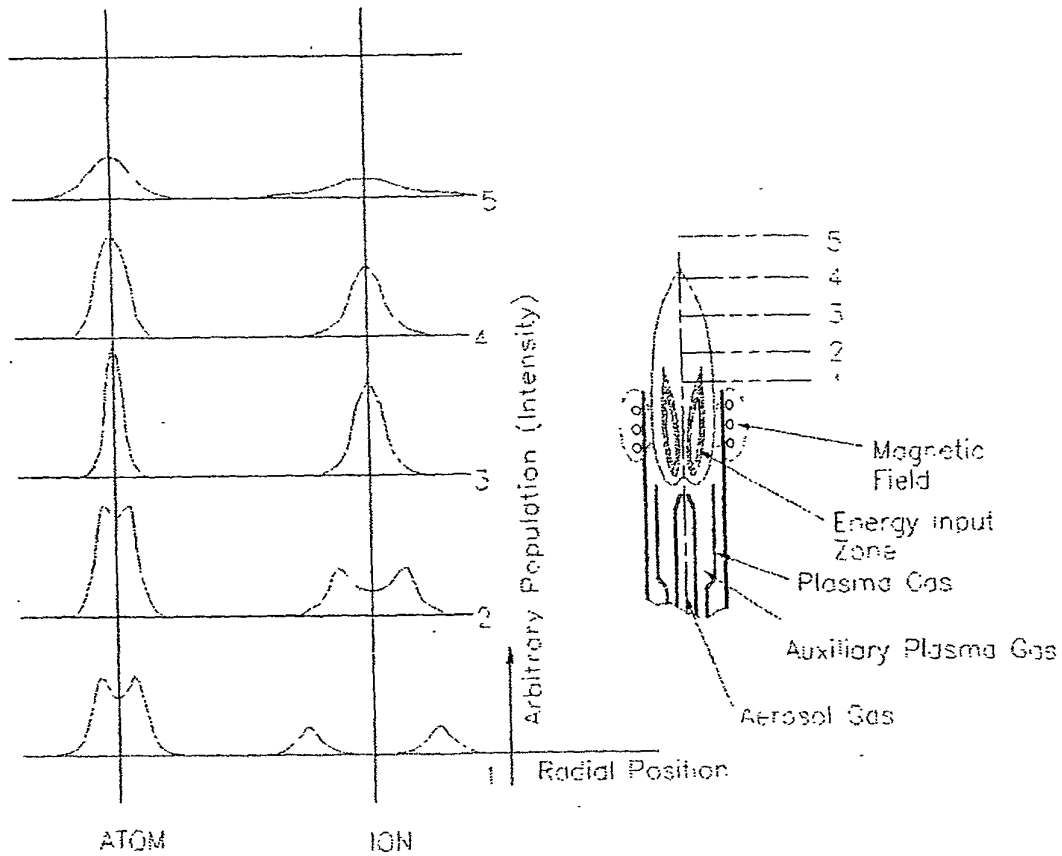


Fig 1: ICP Torch



(all measurements are in millimeters)

Fig. 2: Atom and Ion Distribution in the ICP



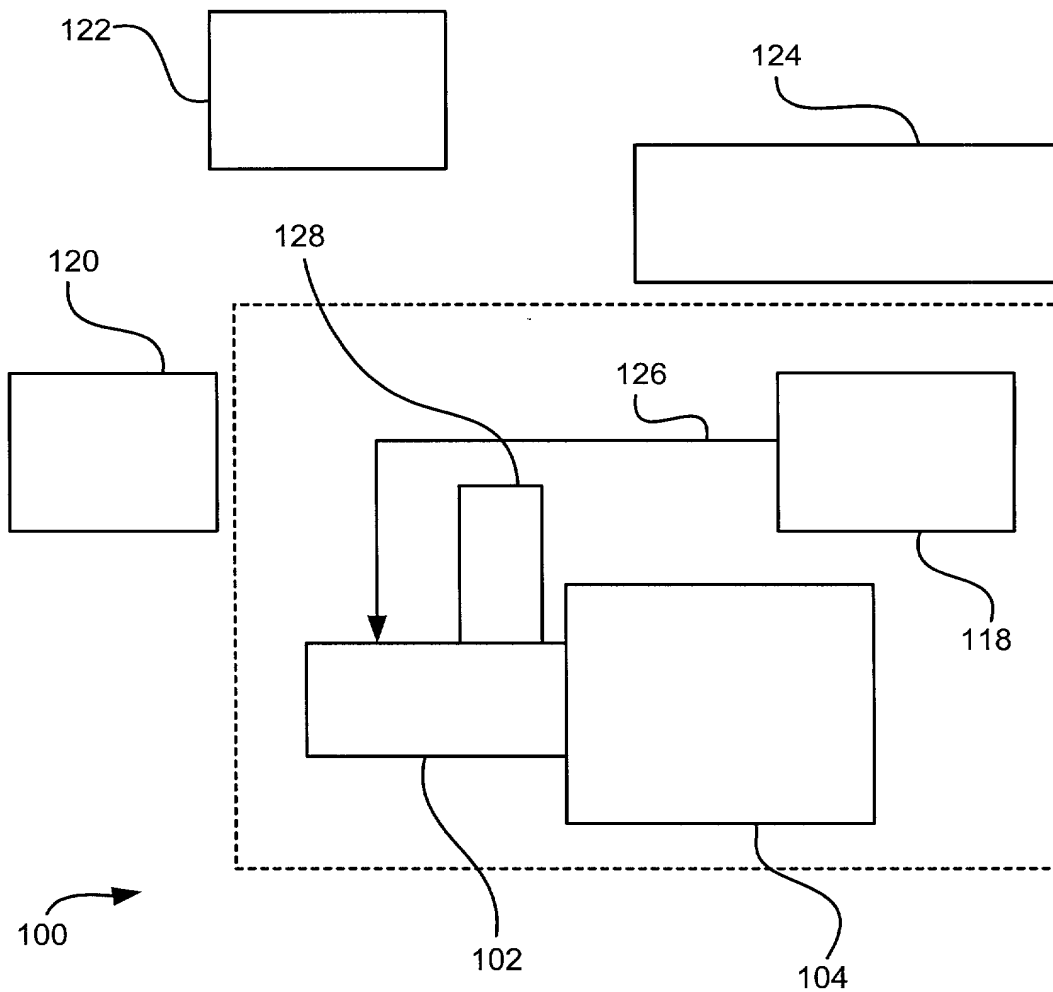
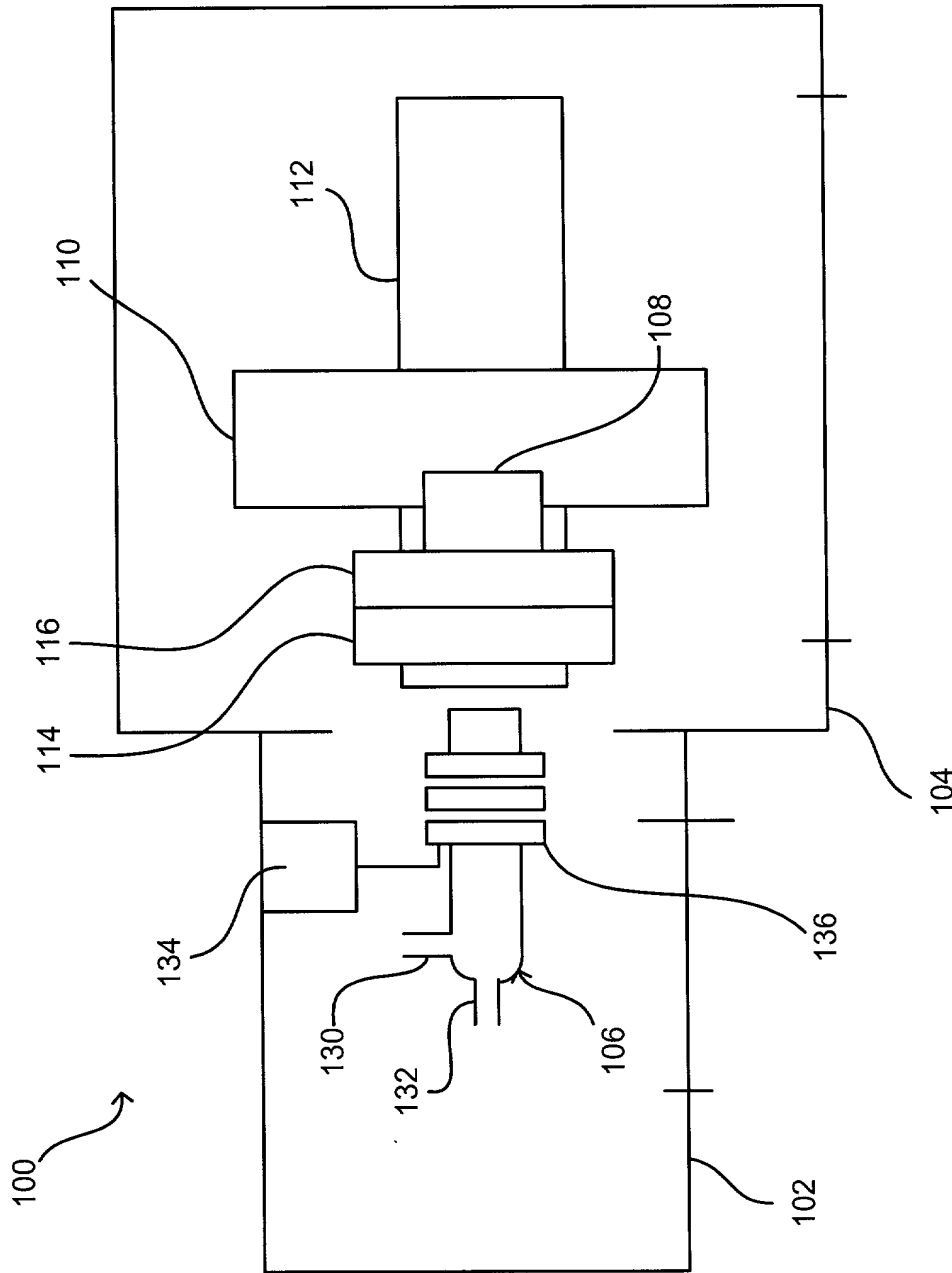


FIG. 3



Title: APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE REACTIVE
ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGE FREE SURFACES

Docket No.: BEAS-01000US1

Applicant(s): Jeffrey W. Carr

Appl. No.: Unknown

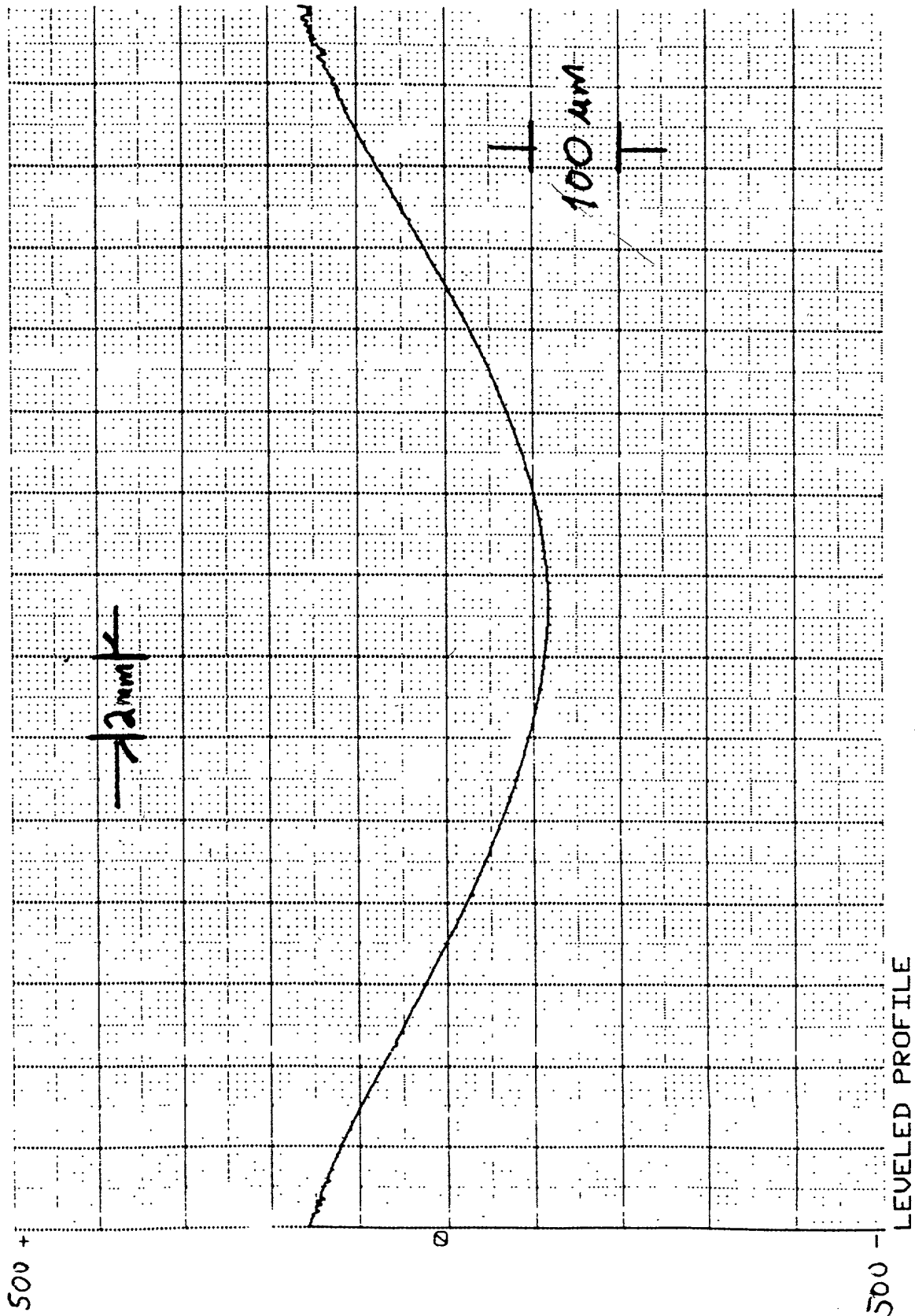
Attorney: Jason D. Lohr

Filed: Herewith

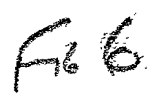
Phone: (415) 362-3800

Express Mail No : EL622697655US

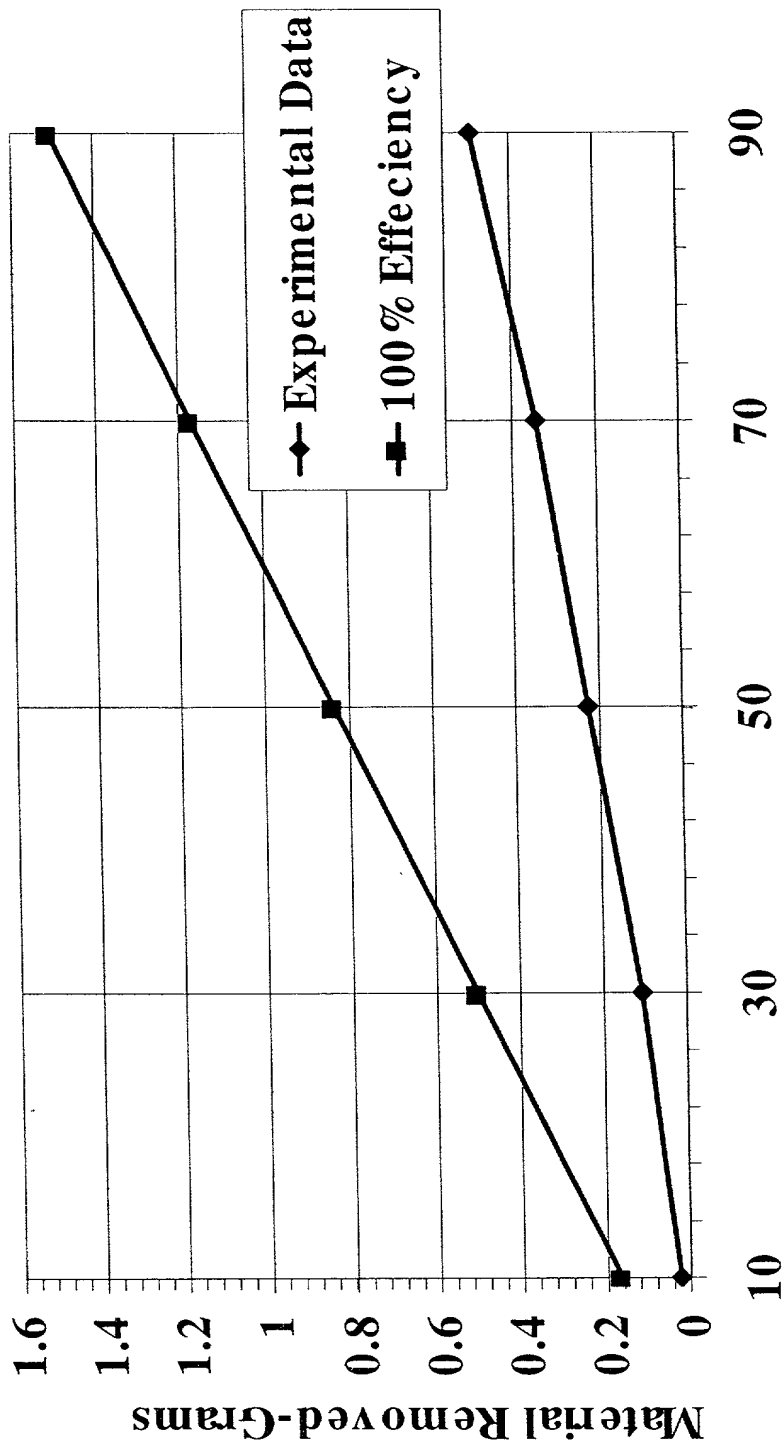
Sheet 5 of 10



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Effect of Reaction Gas Flow Rate on Removal



Reaction Gas Concentration

Fig 7

Effect of Distance from Plasma

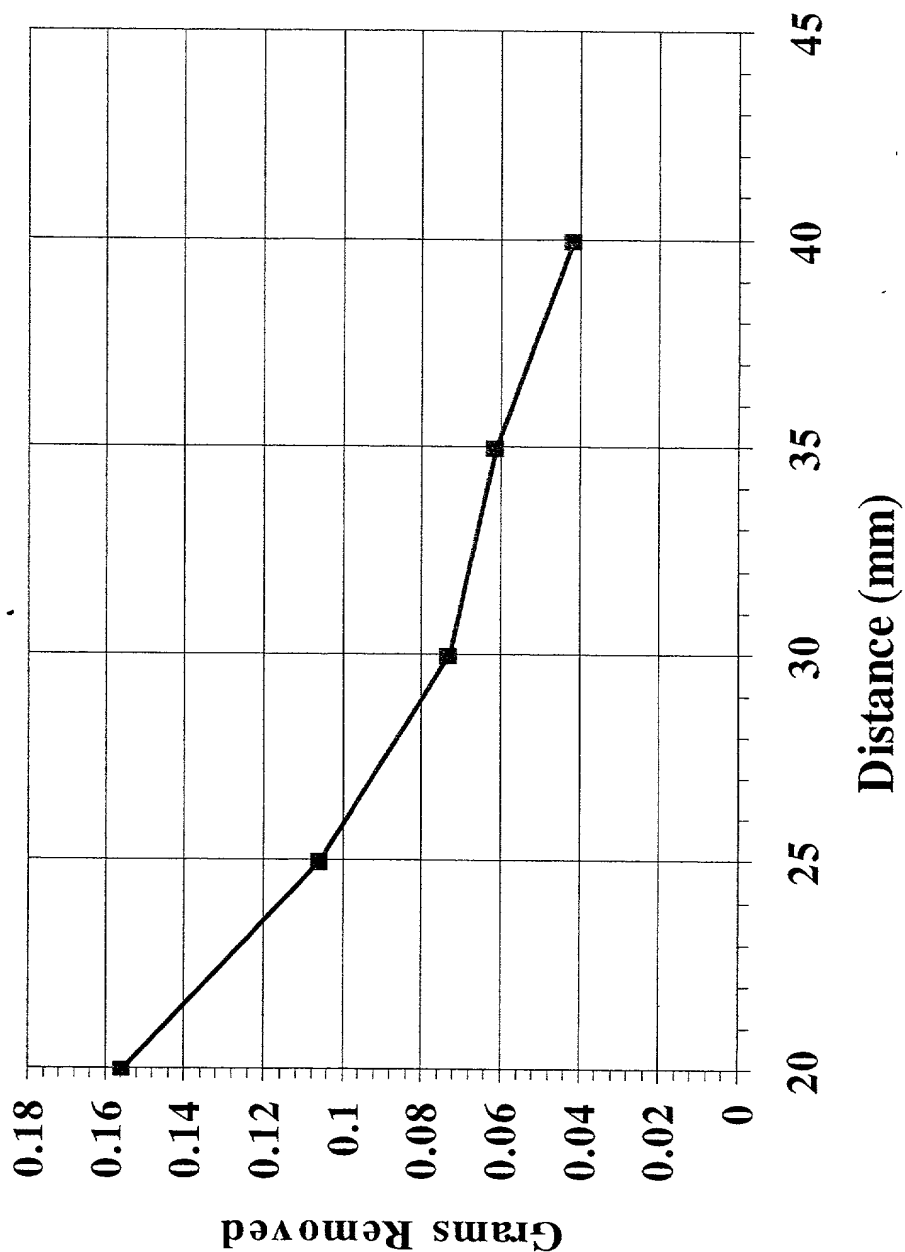


Fig 8

Effect of Reaction Gas Flow Rate on Efficiency

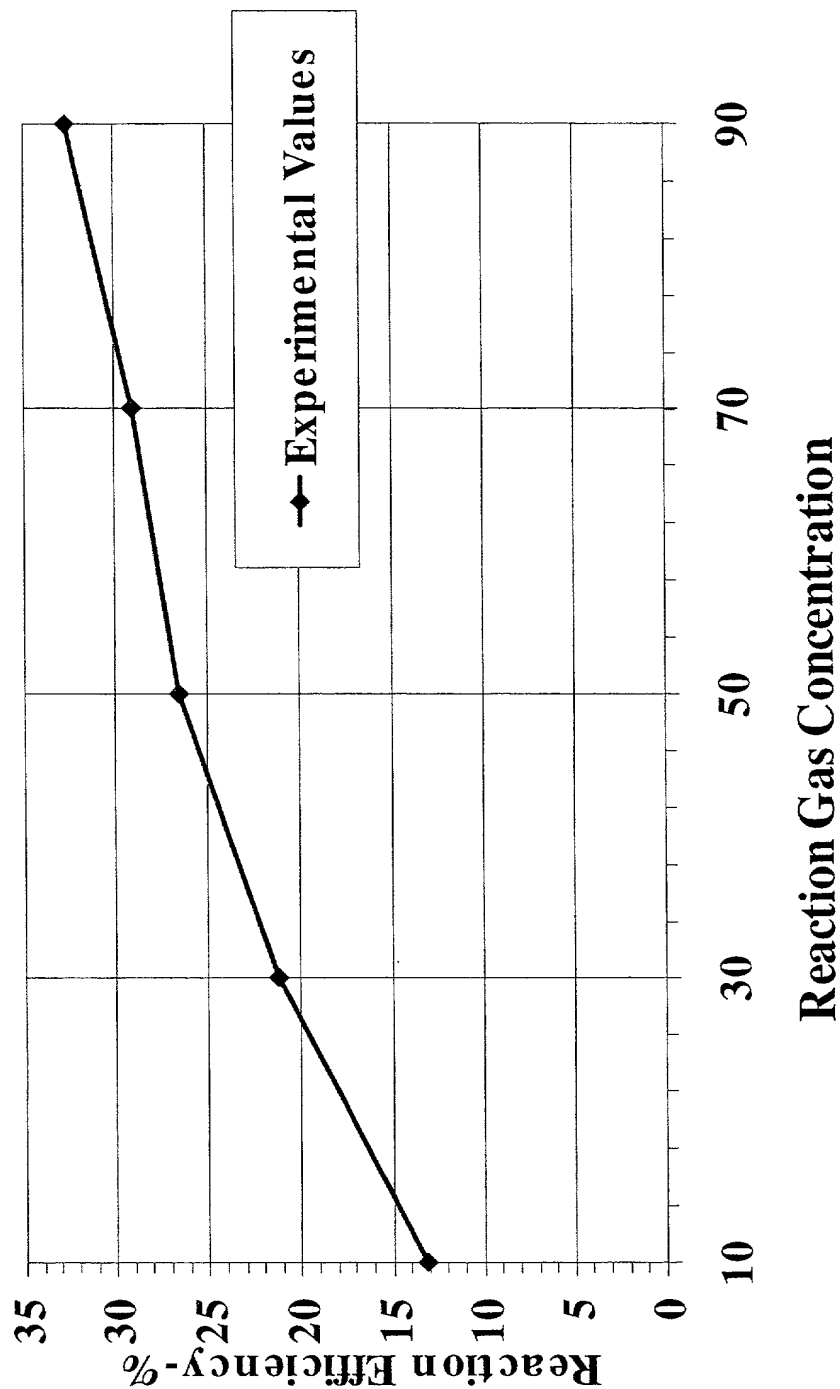


Fig 9

Effect of Distance from Plasma on Efficiency

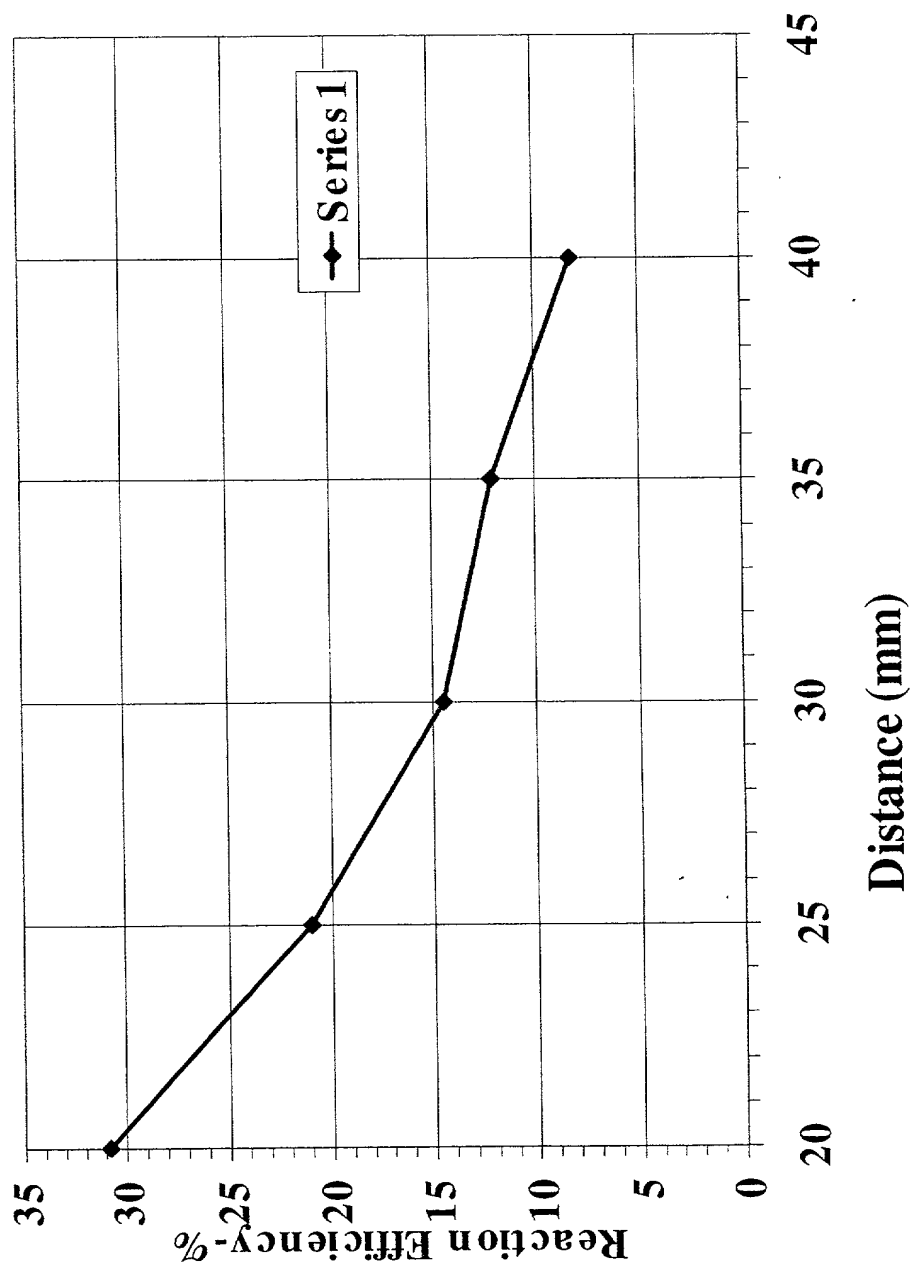


Fig 10